#### PATENT APPLICATION

### IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Tsuyoshi NAKAMURA, et al.

Application No.: To be assigned

Group Art Unit: To be assigned

Confirmation No.: To be assigned

Examiner: To be assigned

Filed: July 11, 2001

For:

NOVEL COPOLYMER, PHOTORESIST COMPOSITION, AND PROCESS FOR

FORMING RESIST PATTERN WITH HIGH ASPECT RATIO

#### PRELIMINARY AMENDMENT

Commissioner for Patents Washington, D.C. 20231

Sir:

## IN THE CLAIMS:

### Please enter the following amended claims:

9. (Amended) A novel copolymer according to claim 1, wherein said novel copolymer has a weight average molecular weight (Mw) in terms of polystyrene of from 7000 to 30000 and a molecular-weight distribution (Mw/Mn, where Mn is a number average molecular weight) of equal to or less than 3.5.

# PRELIMINARY AMENDMENT U.S. Application No. To be assigned

Attorney Docket No. Q65210

## **REMARKS**

The foregoing amendments are made in order to remove multiple dependencies and avoid the Government surcharge. Entry and consideration of this Amendment is respectfully requested.

Respectfully submitted,

Robert J. Seas. J

Registration No. 21,092

SUGHRUE, MION, ZINN, MACPEAK & SEAS, PLLC 2100 Pennsylvania Avenue, N.W. Washington, D.C. 20037-3213 Telephone: (202) 293-7060

Facsimile: (202) 293-7860

Date: July 11, 2001

# APPENDIX VERSION WITH MARKINGS TO SHOW CHANGES MADE

## **IN THE CLAIMS**:

### The claims are amended as follows:

9. (Amended) A novel copolymer according to any one of claims 1 to 8 claim 1, wherein said novel copolymer has a weight average molecular weight (Mw) in terms of polystyrene of from 7000 to 30000 and a molecular-weight distribution (Mw/Mn, where Mn is a number average molecular weight) of equal to or less than 3.5.